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**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re the Application of:

Tae-Wan KIM et al.

Art Unit: 1763

Serial No. 10/713,258

Examiner: Rudy Zervigon

Filed: November 17, 2003

Confirmation No. 4771

For: GAS INJECTION APPARATUS FOR  
SEMICONDUCTOR PROCESSING SYSTEM

Attorney Docket No. 249/410

**AMENDMENT UNDER 37 C.F.R. § 1.111**

Commissioner for Patents  
United States Patent and Trademark Office  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

**INTRODUCTORY COMMENTS**

In response to the Office action dated August 3, 2005, the following amendments and remarks are respectfully submitted in connection with the above-identified application:

**Amendments to the Claims** are reflected in a listing of the claims, which begins on page 2 of this paper.

**Remarks/Arguments** begin on page 7 of this paper.